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#### **U.S. PATENT DOCUMENTS**

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
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## FOREIGN PATENT DOCUMENTS

							TRANSLATI	ЮИ
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	YES	NO
В	BA							

## OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, Etc.)

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<sup>\*</sup>ABSTRACT ONLY

EXAMINER Robert H. Spitar

DATE CONSIDERED Ochober 3, 2005

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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#### \*ABSTRACT ONLY

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